

FABRICATION OF SOLID STATE IMAGE SENSOR

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Inventor: TAJIMA KAZUHISA
Applicant: KYUSHU NIPPON ELECTRIC
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Abstract of JP2001068657

PROBLEM TO BE SOLVED: To obtain a method for fabricating a solid state image sensor in which microlenses can be formed with high yield while reducing variation of shape and thereby variation of lens characteristics. SOLUTION: When a base layer 6 determining the shape of a microlens 10 is formed, it is formed not by etching process but by ordinary photolithography. Since variation in the shape of the base layer 6 can be reduced two-dimensionally and three-dimensionally, microlenses can be formed with high uniformity and lens characteristics are stabilized while increasing the yield.

